



## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Group Art Unit: 1765

Examiner: CHEN, Kin Chan

**RESPONSE** 

Inventor:

BELLMAN, et al.

Serial No:

10/722,769

Filing Date:

November 26, 2003

Title:

METHOD USING MULTI-

COMPONENT COLLOIDAL

ABRASIVES FOR CMP

PROCESSING OF

SEMICONDUCTOR AND **OPTICAL MATERIALS** 

Mail Stop Amendment Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Sir:

## RESPONSE TO THE EXAMINER'S RESTRICTION REQUIREMENT

In response to the Office Action dated December 23, 2004 in the above-captioned application, please enter the following Amendments and Remarks.

No amendment to the specification is being made in this paper.

No amendment to the claims is being made in this paper.

Remarks begin on page 2 in this paper.